IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No.: 10/604,102

Applicant(s): Steegan et al.

Filed.: June 26, 2003

Art Unit: 2815

Dkt. No.: FIS920030051US1

Examiner: Eckert II, George C.

Title: SELECTIVE SILICON-ON-INSULATOR ISOLATION STRUCTURES AND

METHOD

Honorable Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

REQUEST FOR RECONSIDERATION

This Request for Reconsideration is being filed in response to the Office Action mailed on February 28, 2005.

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CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8) Applicant(s): Steegan et al.			Docket No. FIS920030051US1
Application No. 10/604,102	Filing Date 6/26/2003	Examiner Eckert II, George C.	Group Art Unit 2815
Invention: SELECTIVE SILICON-ON-INSULATOR ISOLATION STRUCTURES AND METHOD			
I hereby certify that this	Reg	u <u>est for Reconsideration (9 pa</u> (Identify typs of correspondence)	<u>ges)</u>
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